

## DECLARATION FOR PATENT APPLICATION

02S0045

As a below named inventor, I declare:

that I verily believe myself to be the original, first and sole (if only one individual inventor is listed below) or an original, first and joint inventor (if more than one individual inventor is listed below) of the invention in

PROFILE MEASURING METHOD AND MEASUREMENT APPARATUS USING INTERFERENCE  
OF LIGHT

the specification of which is attached hereto unless the following box is checked.

☐ was filed on \_\_\_\_\_ as United States Application  
or PCT International Application No. \_\_\_\_\_, and  
was amended on \_\_\_\_\_ (if applicable).

I hereby state that I have reviewed and understand the contents of the above identified specification, including the claims, as amended by any amendment referred to above.

I acknowledge the duty to disclose information of which is material to patentability as defined in 37 CFR 1.56.

I hereby claim foreign priority benefits under 35 U.S.C. 119(a)-(d) or 365 (b) of any foreign application(s) for patent or inventor's certificate, or 35 U.S.C. 365(a) of any PCT International application which designated at least one country other than the United States, listed below and have also identified below any foreign application for patent or inventor's certificate, or PCT International application having a filing date before that of the application on which priority is claimed:

<u>Country</u>	<u>Category</u>	<u>Application No.</u>	<u>Filing Date</u>	<u>Priority Claim</u>
Japan	Patent	2001-267786	September 4, 2001	Yes

I hereby appoint the registrants of Oblon, Spivak, McClelland, Maier & Neustadt, P.C., Fourth Floor, 1755 Jefferson Davis Highway, Arlington, Virginia 22202, Customer No. 22850, or any one of them. Send correspondence to Oblon, Spivak, McClelland, Maier & Neustadt, P.C., Fourth Floor, 1755 Jefferson Davis Highway, Arlington, Virginia 22202, Telephone No. (703) 413-3000.

I declare further that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

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## DECLARATION FOR PATENT APPLICATION

I declare further that my citizenship, residence and mailing address are as stated below next to my name:

Inventor: (Signature)

Date

Residence and mailing address

Date: February 15, 2002

Masaaki Adachi

Masaaki Adachi

Citizen of: Japan

53-6, Wakamatsu-machi,  
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Date:

Citizen of: Japan

Date:

Citizen of: Japan

Date:

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Date:

Citizen of: Japan

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Citizen of: Japan

Date:

Citizen of: Japan

Date:

Citizen of: Japan

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DOCKET NO.: 220102US2

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Masaaki ADACHI

SERIAL NO.: NEW APPLICATION

FILED: HEREWITH

FOR: PROFILE MEASURING METHOD AND MEASUREMENT APPARATUS USING  
INTERFERENCE OF LIGHT

**REQUEST FOR SMALL ENTITY STATUS**

This application qualifies for small entity status.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.

Date: 3/1/02

  
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